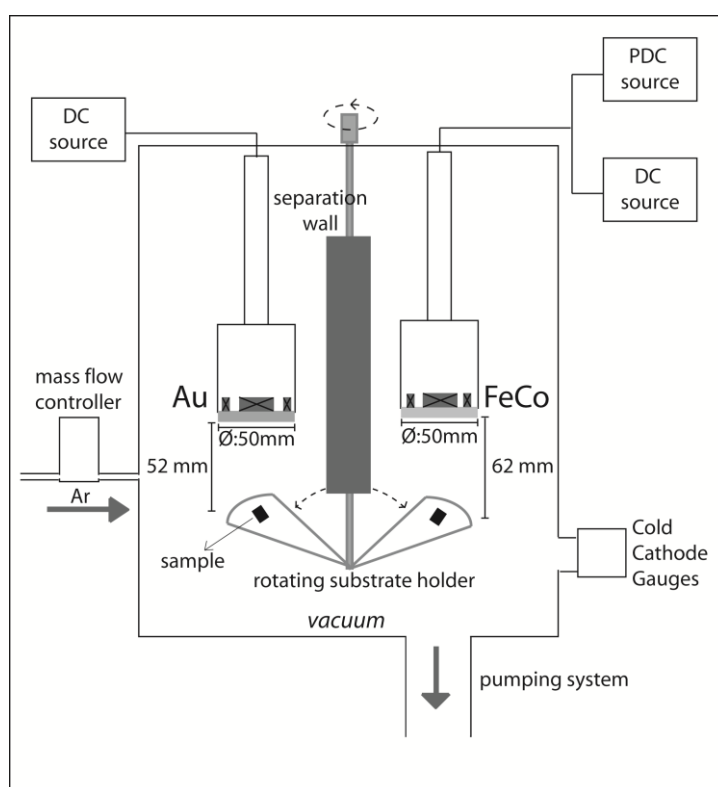


Supplementary Information

Title: Tuning the magnetic properties of FeCo with pulsed DC magnetron sputtering

Authors: M. Abuín, L. Pérez, A. Mascaraque and M. Maicas

1) Schematic of the sputtering system:



This is the schematic of the sputtering system. FeCo magnetron can use either the DC or PDC source. Sample is placed in front of the appropriate magnetron by means of a rotating device. Ar flux is determined by a mass flow controller. Target to substrate distances are specified in the figure.